

INFORMATION DISCLOSURE CITATION IN AN APPLICATION



(PTO-1449)

 ATTY. DOCKET NO.
5917/FET/FET/DV

 SERIAL NO.
09/998,372

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SEP 20 2002
3700 MAIL ROOM

 APPLICANT
Young Joseph PAIK

 FILING DATE
November 30, 2001

 GROUP
3723

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
BA	4,698,766	10/06/87	Entwistle et al.			05/17/85
	4,967,381	10/30/90	Lane et al.			07/06/89
	5,208,765	05/04/93	Turnbull			07/20/90
	5,226,118	07/06/93	Baker et al.			01/29/91
	5,231,585	07/27/93	Kobayashi et al.			06/20/90
	5,420,796	05/30/95	Weling et al.			12/23/93
	5,469,361	11/21/95	Moyne			06/06/94
	5,525,808	06/11/96	Irie et al.			12/20/94
	5,586,039	12/17/96	Hirsch et al.			02/27/95
	5,603,707	02/18/97	Trombetta et al.			11/28/95
	5,664,987	09/09/97	Renteln			09/04/96
	5,812,407	09/22/98	Sato et al.			08/12/97
	5,828,778	10/27/98	Hagi et al.			06/12/96
BA	5,832,224	11/03/98	Fehskens et al.			06/14/96

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
BA	61-171147	08/01/86	Japan				X
	6-184434	07/05/94	Japan				X
	0 621 522 A2	10/26/94	Europe			X	
	8-50161	02/20/96	Japan				X
BA	8-304023	11/22/96	Japan				X

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BA	February 1984. "Method and Apparatus of in Situ Measurement and Overlay Error Analysis for Correcting Step and Repeat Lithographic Cameras." <i>IBM Technical Disclosure Bulletin</i> , pp. 4855-4859.
BA	October 1984. "Method to Characterize the Stability of a Step and Repeat Lithographic System." <i>IBM Technical Disclosure Bulletin</i> , pp. 2857-2860.
EXAMINER	DATE CONSIDERED 02/20/04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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BR	5,859,964	01/12/99	Wang et al.			10/25/96
	5,863,807	01/26/99	Jang et al.			03/15/96
	5,870,306	02/09/99	Harada			06/13/97
	5,903,455	05/11/99	Sharpe, Jr. et al.			12/12/96
	5,916,016	06/29/99	Bothra			10/23/97
	5,923,553	07/13/99	Yi			10/05/96
	5,930,138	07/27/99	Lin et al.			09/10/97
	5,940,300	08/17/99	Ozaki			05/08/97
	5,960,214	09/28/99	Sharpe, Jr. et al.			12/04/96
	5,963,881	10/05/99	Kahn et al.			10/20/97
	5,982,920	11/09/99	Tobin, Jr. et al.			01/08/97
	6,041,270	03/21/00	Steffan et al.			12/05/97
	6,078,845	06/20/00	Friedman			10/25/96
	6,112,130	06/20/00	Fukuda et al.			10/01/97
BR	6,148,246	11/14/00	Kawazome			06/10/98

FOREIGN PATENT DOCUMENTS







EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
BR	0 747 795 A2	12/11/96	Europe			X	
	10-173029	06/26/98	Japan				X
	0 895 145 A1	02/03/99	Europe			X	
BR	11-126816	05/11/99	Japan				X

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)


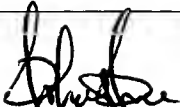
BR	Schmid, Hans Albrecht. 1995. "Creating the Architecture of a Manufacturing Framework by Design Patterns." Austin, Texas: OOPSLA.
BR	Baliga, John. July 1999. "Advanced Process Control: Soon to be a Must." Cahners Semiconductor International. www.semiconductor.net/semiconductor/issues/issues/1999/jul99/docs/feature1.asp
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				APPLICANT Young Joseph PAIK			
				FILING DATE November 30, 2001		GROUP 3723	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
 ↓	6,175,777	01/16/01	Kim	—	—	01/16/98	
	6,178,390	01/23/01	Jun	—	—	09/08/98	
	6,185,324	02/06/01	Ishihara et al.	—	—	01/31/95	
	6,192,291	02/20/01	Kwon	—	—	10/08/98	
	6,197,604	03/06/01	Miller et al.	—	—	10/01/98	
	6,211,094	04/03/01	Jun et al.	—	—	08/23/99	
	6,226,792	05/01/01	Goiffon et al.	—	—	10/14/98	
	6,230,069	05/01/01	Campbell et al.	—	—	06/26/98	
	6,236,903	05/22/01	Kim et al.	—	—	09/25/98	
	6,240,330	05/29/01	Kurtzberg et al.	—	—	05/28/97	
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
 ↓	11-135601	05/21/99	Japan	—	—		X
	WO 00/05759	02/03/00	WO	—	—	X	
	WO 00/35063	06/15/00	WO	—	—	X	
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 ↓	July 5, 2001. "Motorola and Advanced Micro Devices Buy ObjectSpace Catalyst Advanced Process Control Product for Five Wafer Fabs." Semiconductor FABTECH. www.semiconductorfabtech.com/industry.news/9907/20.07.shtml						
	October 15, 2001. Search Report prepared by the Austrian Patent Office for Singapore Patent Application No. 200004286-1.						
	Johnson, Bob. June 10, 2002. "Advanced Process Control Key to Moore's Law." Gartner, Inc.						
	July 9, 2002. International Search Report prepared by the European Patent Office for PCT/US01/24910.						
	July 29, 2002. International Search Report prepared by the European Patent Office for PCT/US01/27407.						
 ↓	Sonderman, Thomas. 2002. "APC as a Competitive Manufacturing Technology: AMD's Vision for 300mm." AEC/APC.						
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EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
BR	6,240,331	05/29/01	Yun	—	—	08/18/98	
	6,248,602	06/19/01	Bode et al.	—	—	11/01/99	
	6,252,412	06/26/01	Talbot et al.	—	—	01/08/99	
	6,263,255	07/17/01	Tan et al.	—	—	08/18/98	
	6,292,708	09/18/01	Allen et al.	—	—	06/11/98	
	6,298,274	10/02/01	Inoue	—	—	06/01/99	
	6,303,395	10/16/01	Nulman	—	—	06/01/99	
V	6,345,315	02/05/02	Mishra	—	—	08/12/98	
BR	6,366,934	04/02/02	Cheng et al.	—	—	06/02/99	
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
BR	WO 00/79355 A1	12/28/00	WO	—	—	X	
V	2001-76982	03/23/01	Japan	—	—		X
BR	WO 01/33501 A1	06/19/01	WO	—	—	X	
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